



#1767

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Yong-Pil Han et al.

Serial No.: 09/498,303

Filed: February 4, 2000

For: HF VAPOR PHASE WAFER CLEANING AND OXIDE ETCHING

Group Art Unit: 1763

Examiner: T. Dang

THE ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, DC 20231

I hereby certify under 37 CFR 1.8(a)
that this correspondence is being
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GROUP 1700

Theresa A. Lober
July 12, 2002

PETITION FOR ONE-MONTH EXTENSION OF TIME UNDER 37 C.F.R. 1.136(a)

Hereby is petitioned the Assistant Commissioner for Patents to extend for the patent application referenced above the period for response to the Examiner's Action mailed March 13, 2001, for ONE (1) month, extending the last day of the response period from June 13, 2002, up to and including July 15, 2002. A response to the Examiner's Action is being filed on even date herewith.

Please apply the \$200.00 fee under 1.17(a)(2) to Deposit Account No. 19-2553. Please apply any deficiency in the stated fee, any other required fees, and please apply any overpayment, to Deposit Account No. 19-2553.

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Respectfully submitted,

Date

July 12, 2002

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